

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Hai Cong, et al. : Confirmation No.: 4993
Serial No.: 10/767,292 : Art Unit: 2812
Filed: 1/29/2004 : Examiner: Mohsen Ahmadi
For: A NOVEL METHOD TO :
CONTROL DUAL
DAMASCENE TRENCH
ETCH PROFILE AND
TRENCH DEPTH
UNIFORMITY

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE AFTER FINAL REJECTION
UNDER 37 C.F.R. §1.116

Sir/Madam:

The following Remarks are submitted under 37 C.F.R. §1.116 in response to the Final Office Action mailed December 19, 2006. After this introductory section, there are Remarks starting on a separate page.

Reconsideration of the rejections is respectfully requested.